

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/810,387
Filing Date March 15, 2001
Confirmation No. 8779
Inventor Craig M. Carpenter et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1792
Examiner R. Zervigon
Attorney's Docket No. MI22-1559
Title: Chemical Vapor Deposition Apparatuses and Deposition Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO/SB/08A-B

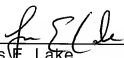
In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO/SB/08. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (37 CFR § 1.98(a)(2)). No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed before the mailing of a first office action after the filing of an RCE on October 14, 2008. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee, any underpayment, or credit any overpayment specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 04 Nov 2008

By: 
James F. Lake
Reg. No. 44854